



Subst. Form PTO-1449

Atty. Docket No.: D/A0597
XER 2 0368

Serial No.: 09/725,836

APPLICANT'S(S) INFORMATION
DISCLOSURE STATEMENT

Applicant(s): Decai Sun, et al.

Filing Date: November 29, 2000

Group: 2831

U.S. PATENT DOCUMENTS

Initial*		Document No.	Date	Name	Class	Subcl.	Filing Date
	AA	6,243,194 B1	05JE2001	Brazas, Jr. et al.			
	AB	6,456,420 B1	24SE2002	Goodwin-Johansson			
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	AD	5,870,007	09FE1999	Carr et al.			
	AE	5,677,783	14OC1997	Bloom et al.			
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	AG	5,069,742	03DE1991	Bleil			
	AH	5,490,034	06FE1996	Zavracky et al.			
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		Document No.	Date	Country	Class	Subcl.	Translation?
	AL	WO 94/03786	17FE1994	PCT			English
	AM	EP 0 502 222 A1	09SE1992	EPC			English
	AN						
	AO						
	AP						

OTHER ART

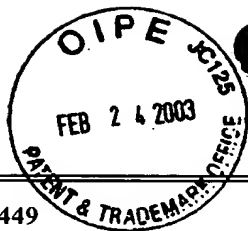
	AR	European Search Report; Application No. 01127498.2-1524; 09 April 2002; Examiner Michel, A.
	AS	MOTAMEDI, M. Edward; <i>Development of Micro-Electro-Mechanical Optical Scanner</i> ; Society of Photo Optical Instrumentation Engineers, 36(5) pp. 1346-1353 (May 1997);.
	AT	European Search Report; Application No. 01127729.0-2217; 09 April 2002; Examiner Michel, A.

Examiner:

Jinhee Lee

Date Considered: 3/14/03

* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if in conformance and not considered. Include copy of this form with next communication to applicant.



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	BQ	WIBBELER et al.; <i>Parasitic Charging of Dielectric Surfaces in Capacitive Micro-Electro-Mechanical Systems (MEMS); Sensors and Actuators A</i> , 71 (1998) 74-80.
	BR	WALKER et al.; <i>Focused Ion Beam Processing for Microscale Fabrication; Microelectronic Engineering</i> 30 (1996) 517-522.
	BS	SYMS, Richard R. A.; <i>Refractive Collimating Microlens Arrays by Surface Tension Self-Assembly; IEEE Photonics Technology Letters</i> , Vol. 12, No. 11, November 2000, pp. 1507-1509.

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